



US00D851142S

(12) **United States Design Patent**
Kamimura et al.

(10) **Patent No.:** **US D851,142 S**
(45) **Date of Patent:** **** Jun. 11, 2019**

- (54) **PRESSING MEMBER FOR SUBSTRATE POLISHING APPARATUS**
- (71) Applicant: **EBARA CORPORATION**, Tokyo (JP)
- (72) Inventors: **Kenji Kamimura**, Tokyo (JP);
Masayuki Nakanishi, Tokyo (JP);
Satoru Yamamoto, Tokyo (JP);
Yasuyuki Miyasawa, Tokyo (JP); **Kenji Kodera**, Tokyo (JP)
- (73) Assignee: **EBARA CORPORATION**, Tokyo (JP)
- (**) Term: **15 Years**
- (21) Appl. No.: **29/659,981**
- (22) Filed: **Aug. 14, 2018**

Related U.S. Application Data

- (62) Division of application No. 29/592,889, filed on Feb. 3, 2017, now Pat. No. Des. 834,075.

(30) **Foreign Application Priority Data**

Aug. 5, 2016 (JP) 2016-016852
 Aug. 5, 2016 (JP) 2016-016853
 Aug. 5, 2016 (JP) 2016-016854
 Aug. 5, 2016 (JP) 2016-016855

- (51) **LOC (11) Cl.** **15-09**
- (52) **U.S. Cl.**
USPC **D15/126**
- (58) **Field of Classification Search**
USPC D8/70, 71; D15/126, 138
CPC B24B 9/065; B24B 21/004; B24B 37/27
See application file for complete search history.

(56) **References Cited**

U.S. PATENT DOCUMENTS

1,867,620 A 7/1932 Forse
 3,867,797 A 2/1975 Meier

5,271,185 A 12/1993 Hosokawa
 5,335,530 A 8/1994 Homm
 5,445,554 A 8/1995 Hosokawa
 5,476,413 A 12/1995 Hasegawa et al.
 5,476,414 A 12/1995 Hirose et al.
 5,493,380 A 2/1996 Saitou et al.
 5,564,965 A 10/1996 Tanaka et al.
 5,960,729 A 10/1999 Matsumoto et al.
 5,973,271 A 10/1999 Fujita
 6,248,005 B1 6/2001 Ozaki
 7,955,113 B2 6/2011 Chang
 D834,075 S * 11/2018 Kamimura D15/126
 2001/0041523 A1 11/2001 Bonachera et al.
 2002/0061211 A1 5/2002 Kamijo et al.
 2002/0137439 A1 9/2002 Hakomori et al.
 2002/0164930 A1 11/2002 Hakomori
 2003/0186624 A1 10/2003 Koike et al.
 2004/0087253 A1 5/2004 Mahadev et al.

(Continued)

Primary Examiner — Patricia A Palasik

(74) *Attorney, Agent, or Firm* — Pearne & Gordon LLP

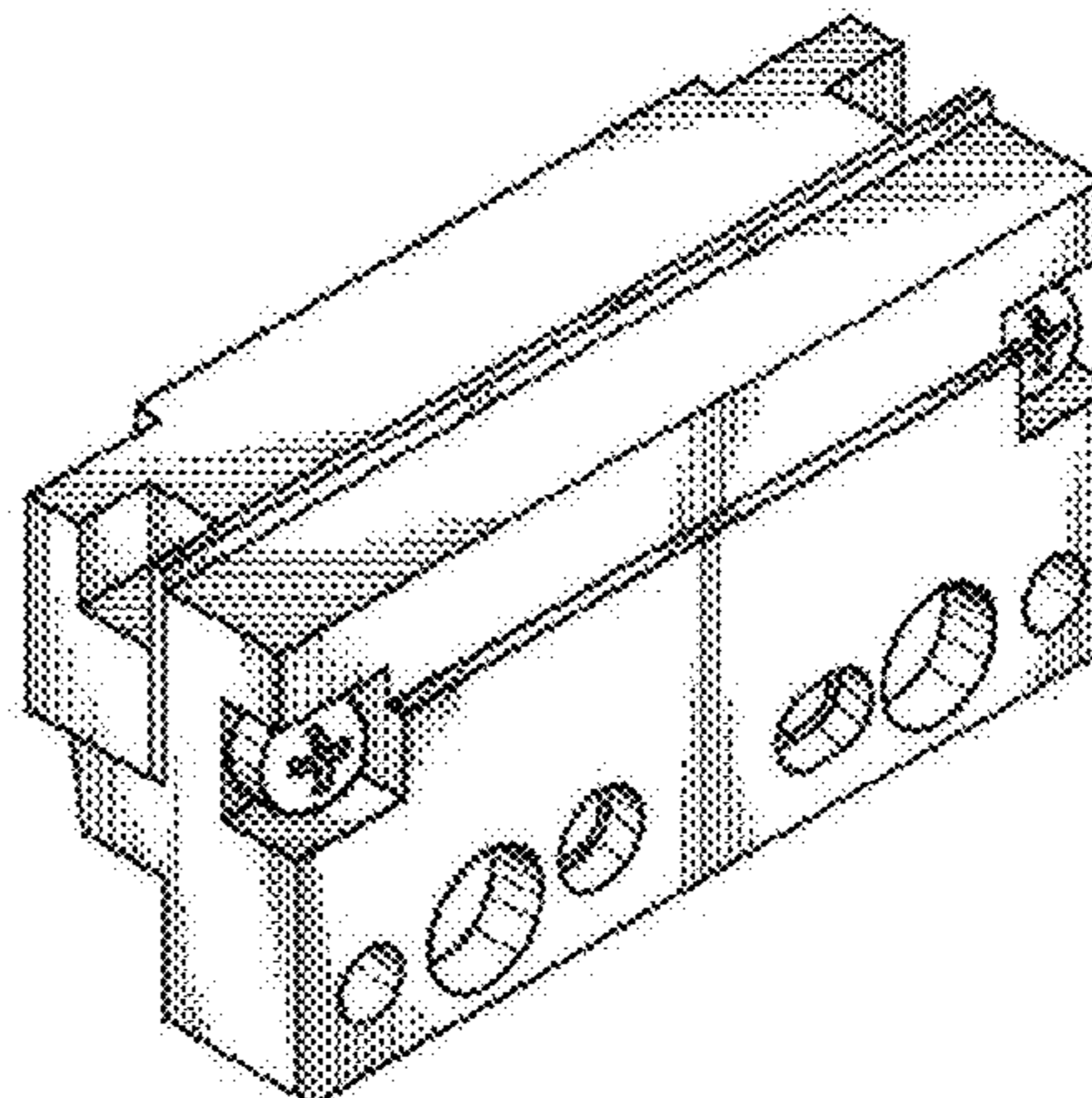
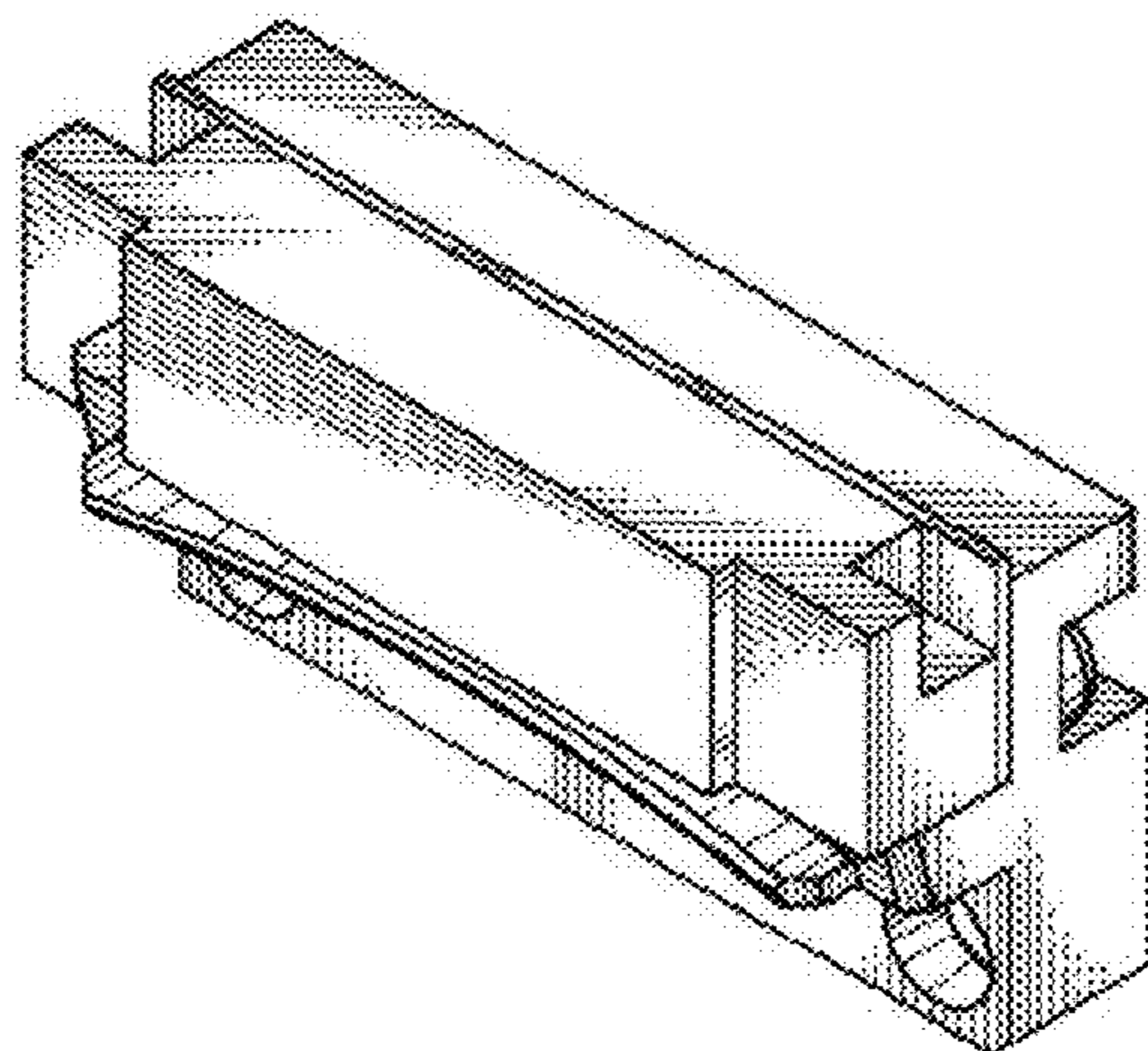
(57) **CLAIM**

The ornamental design for a pressing member for a substrate polishing apparatus, as shown and described.

DESCRIPTION

FIG. 1 is a first perspective view, observed from a front of a pressing member for a substrate polishing apparatus showing our new design;
 FIG. 2 is a second perspective view, observed from a rear thereof;
 FIG. 3 is a front view thereof;
 FIG. 4 is a rear view thereof;
 FIG. 5 is a top view thereof;
 FIG. 6 is a bottom view thereof; and,
 FIG. 7 is a right-side view thereof, a left-side view being a mirror image thereof.

1 Claim, 2 Drawing Sheets



(56)

References Cited

U.S. PATENT DOCUMENTS

2004/0180610	A1	9/2004	Togawa
2005/0275398	A1	12/2005	Yamashita
2008/0085658	A1	4/2008	Katsuoka et al.
2008/0182482	A1	7/2008	Nomura et al.
2009/0011651	A1	1/2009	Lin et al.
2009/0177083	A1	7/2009	Matsumura
2009/0264053	A1	10/2009	Manens et al.
2010/0170716	A1	7/2010	Ishida et al.
2011/0003540	A1	1/2011	Takahashi et al.
2011/0132956	A1	6/2011	Kempka, Jr.
2011/0237164	A1	9/2011	Seki et al.
2014/0042005	A1	2/2014	Lee

* cited by examiner

FIG.1

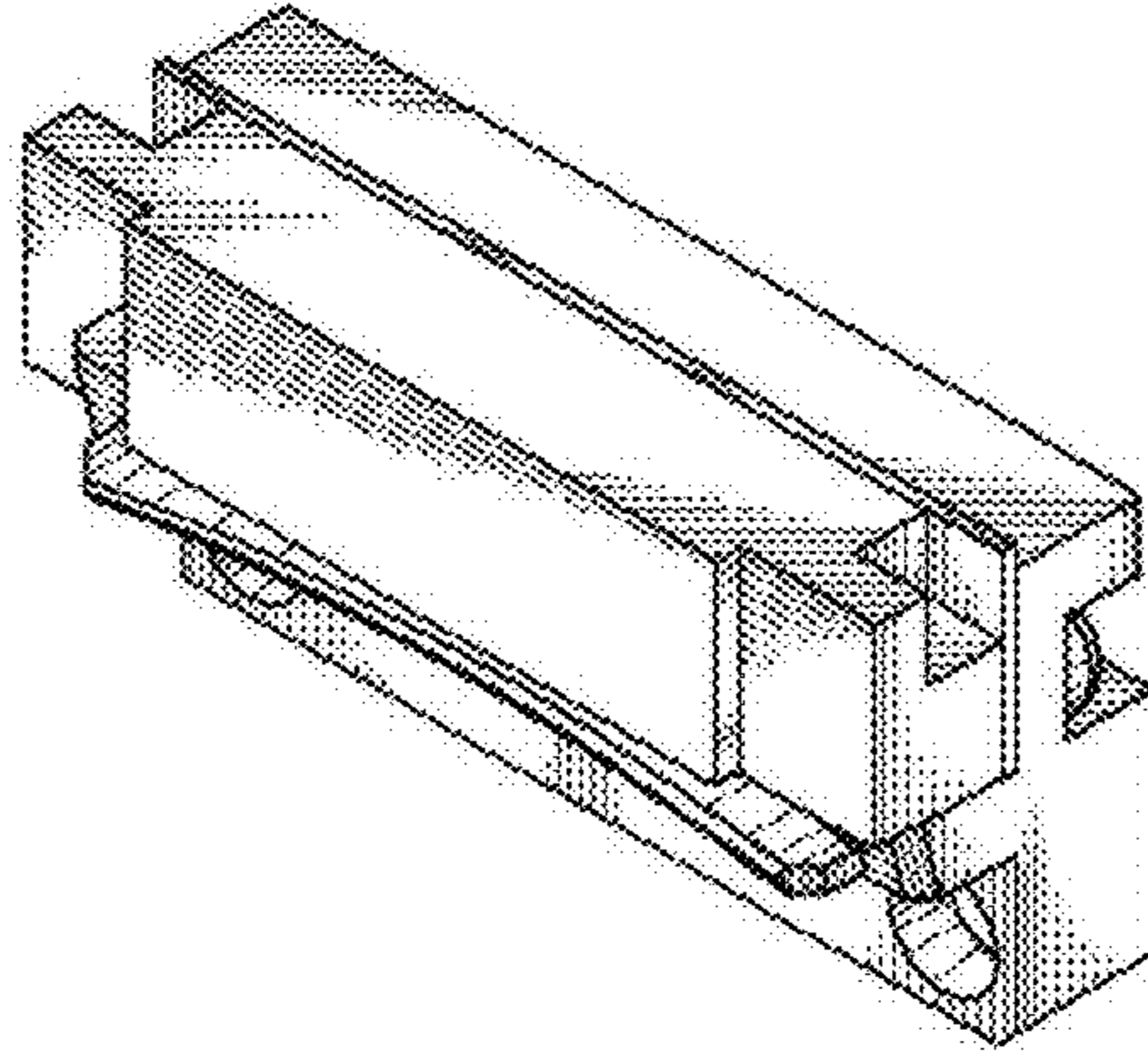


FIG.2

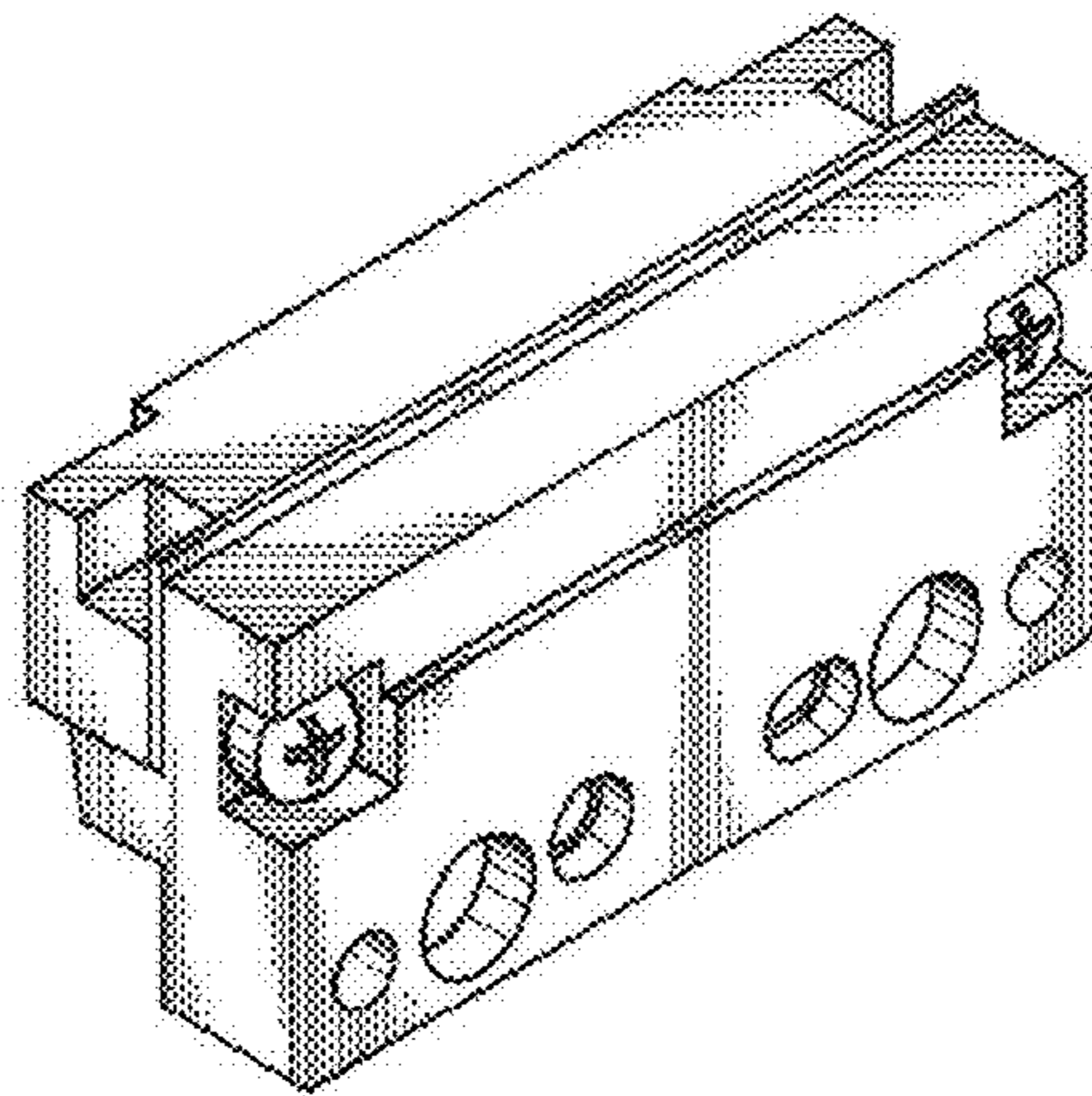


FIG.3

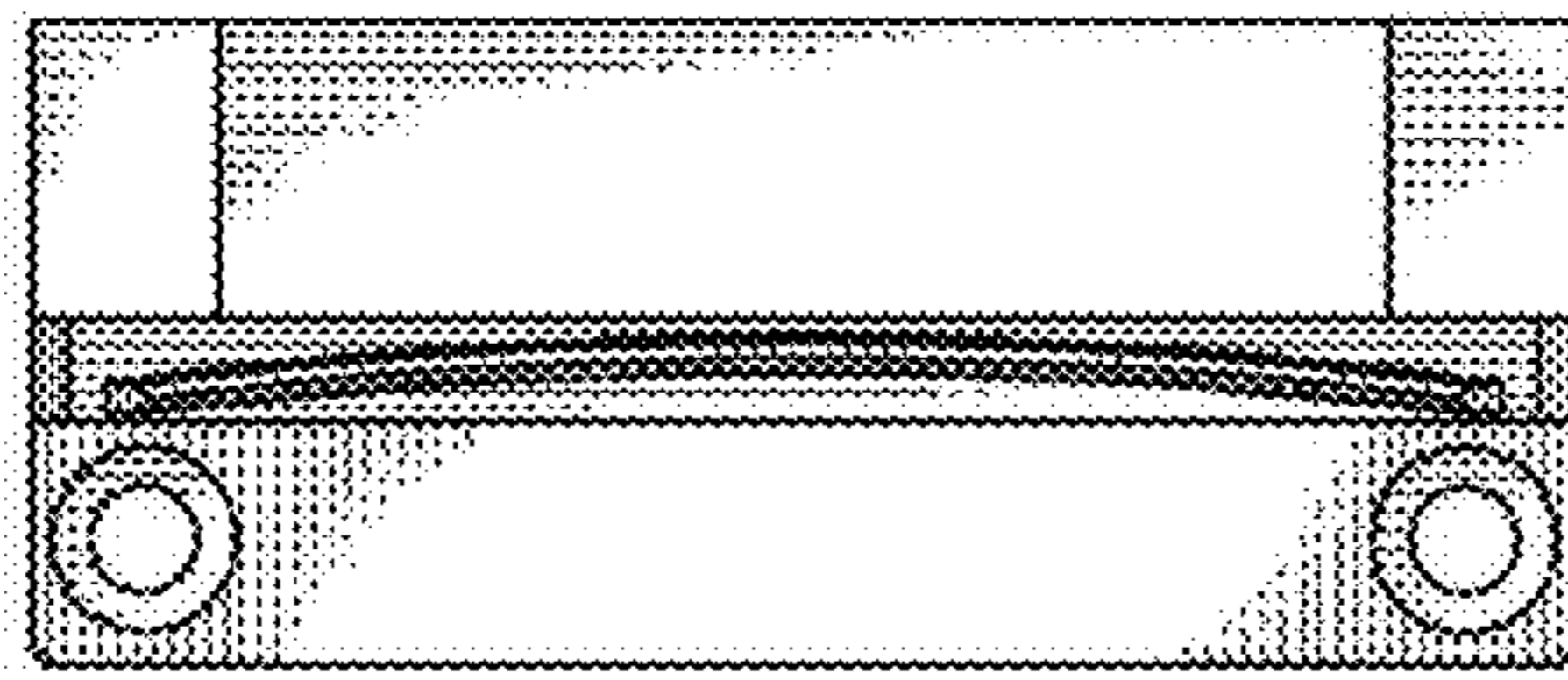


FIG.7

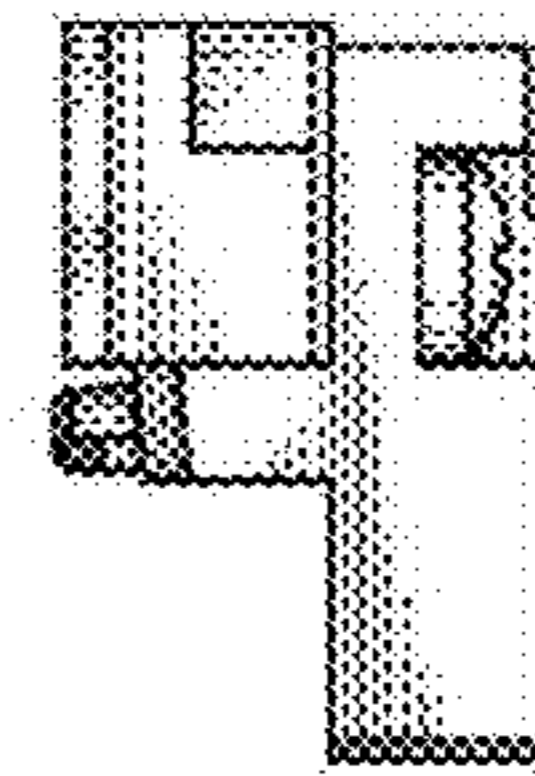


FIG.4

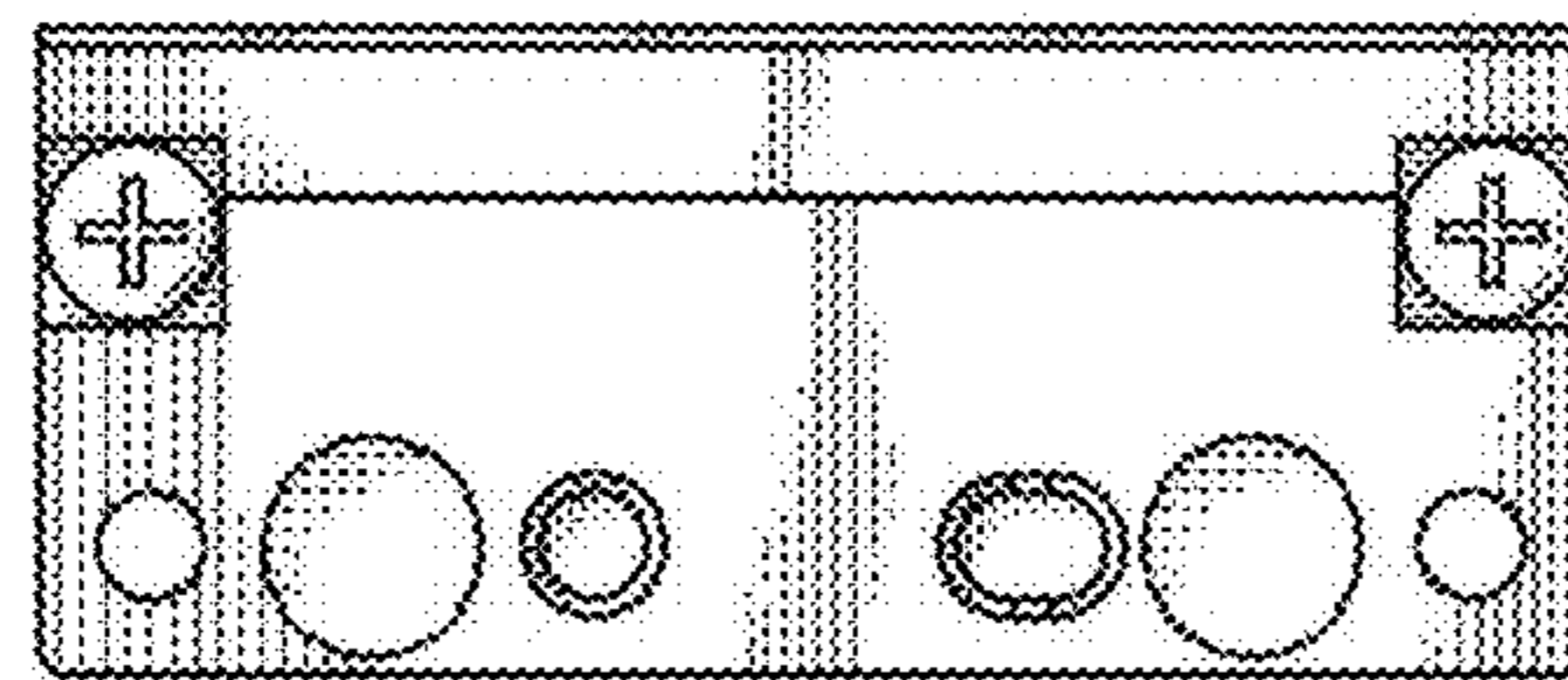


FIG.5

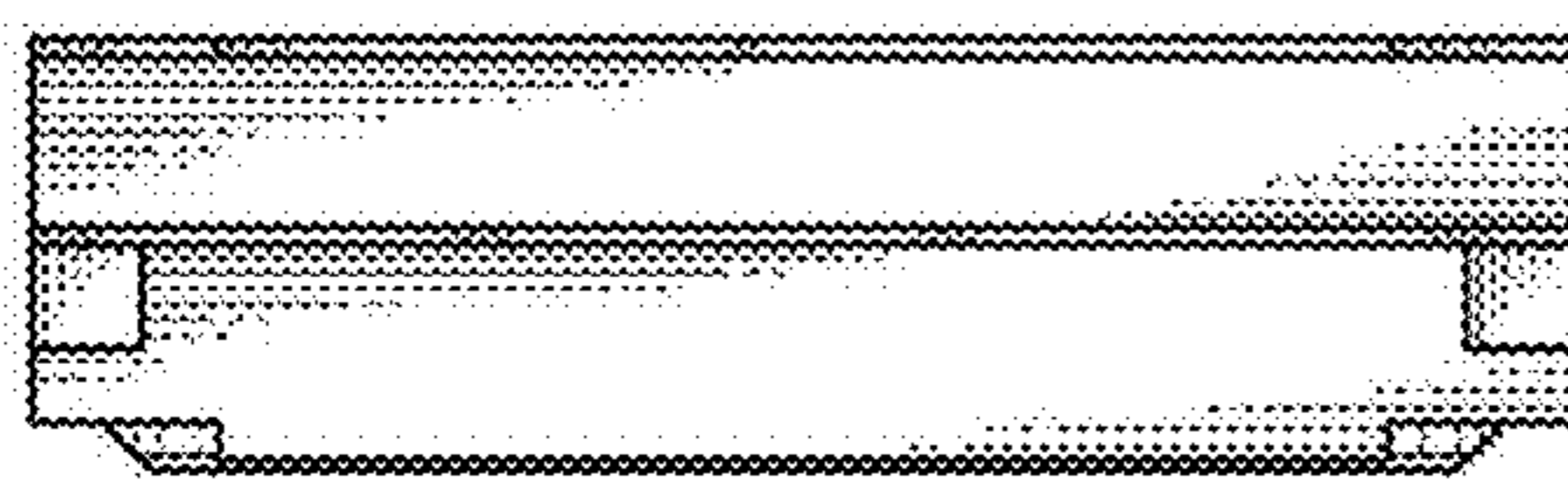


FIG.6

